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APPLICANTS

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** CONTINUING DATA *****

This application is a DIV of 09/641,125 08/16/2000 PAT 6,645,676 *a2*

** FOREIGN APPLICATIONS *****

JAPAN 11-232358 08/19/1999 *a2*

IF REQUIRED, FOREIGN FILING LICENSE GRANTED

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Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no	STATE OR COUNTRY JAPAN	SHEETS DRAWING 9	TOTAL CLAIMS 1	INDEPENDENT CLAIMS 1
35 USC 119 (a-d) conditions met <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance	Verified and Acknowledged <i>a2</i> Examiner's Signature Initials			

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TITLE

Electron beam exposure mask, electron beam exposure method, method of fabricating semiconductor device, and electron beam exposure apparatus

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